

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No. : (To Be Assigned) Confirmation No. : (TBA)
PCT/JP2004/009026
First Named Inventor : Hiroshi KANNAN
Filed : December 27, 2005
TC/A.U. : (To Be Assigned)
Examiner : (To Be Assigned)
Docket No. : 010986.57272US
Customer No. : 23911
Title : Plasma Generation Method, Cleaning Method, and
Substrate Processing Method

PRELIMINARY AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Please enter the following amendments to the specification and claims, as amended by way of Annexes to the International Preliminary Examination Report for PCT/JP2004/009026, prior to the examination of the application during the U.S. National Phase.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 22 of this paper.